

Fig.1a
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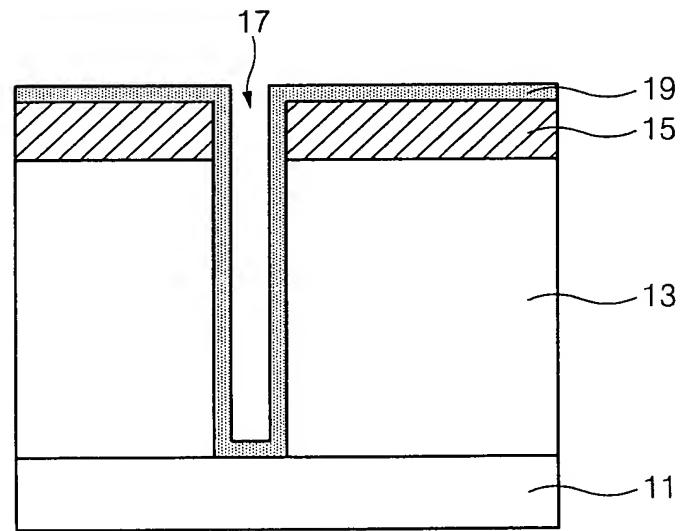


Fig.1b
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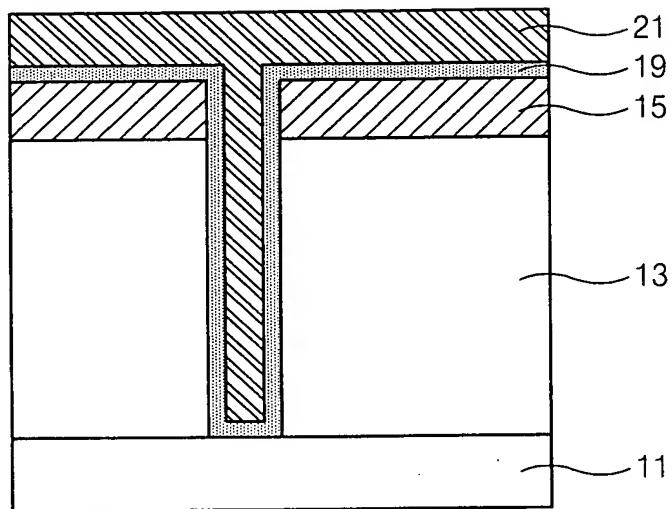


Fig.1c
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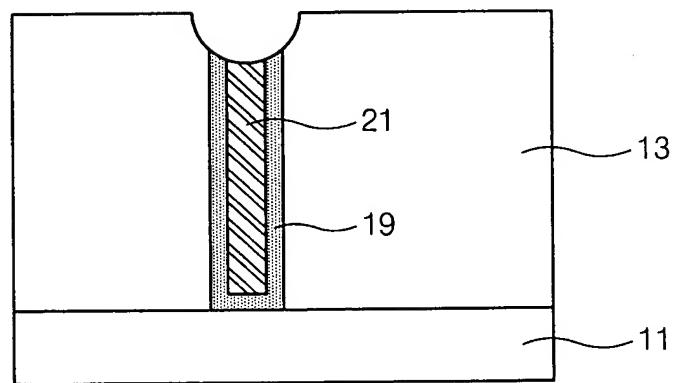


Fig.1d
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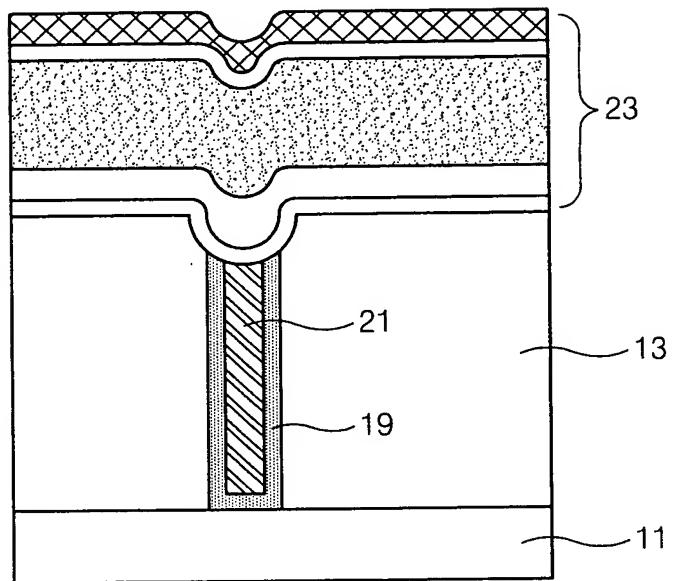


Fig.1e
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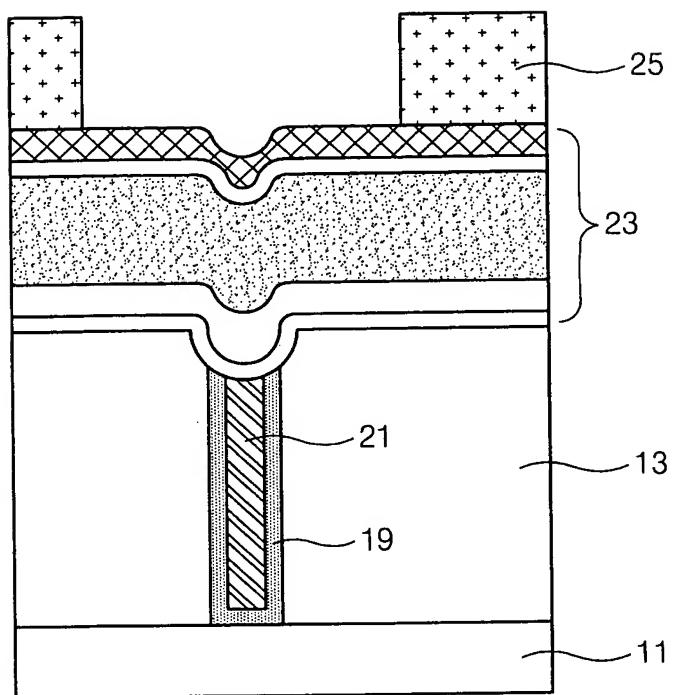


Fig.1f
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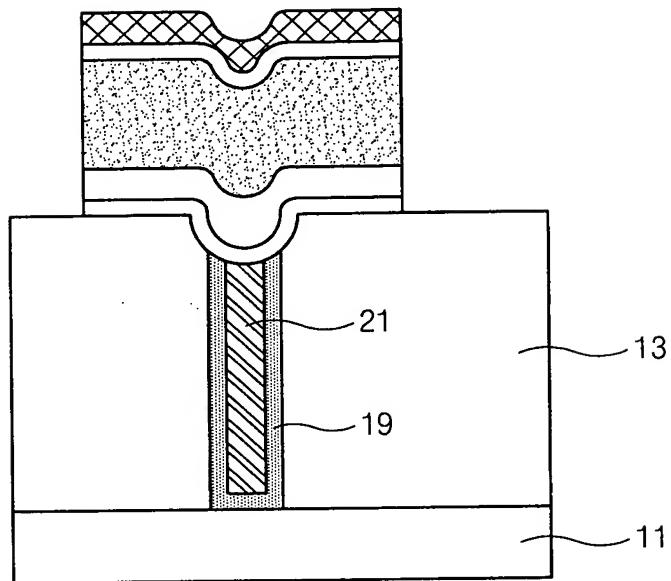


Fig.1g
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Won Hwa JIN
"Method for Forming Metal Line
of Semiconductor Device"
Attorney Docket No.: 40296-0026

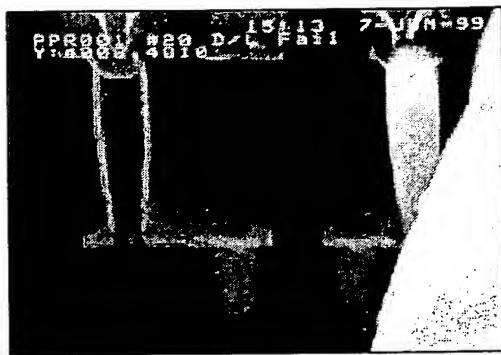


Fig.2a
<Prior Art>



Fig.2b
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Won Hwa JIN
"Method for Forming Metal Line
of Semiconductor Device"
Attorney Docket No.: 40296-0026

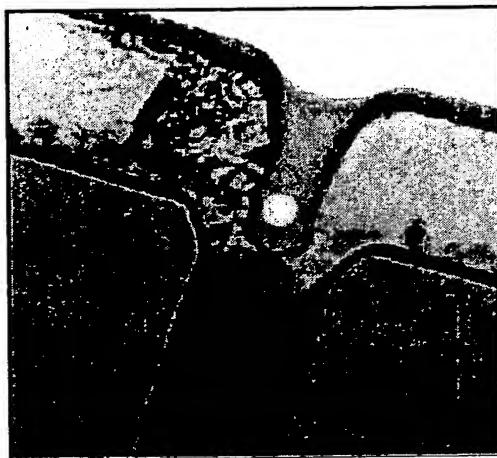


Fig.2c

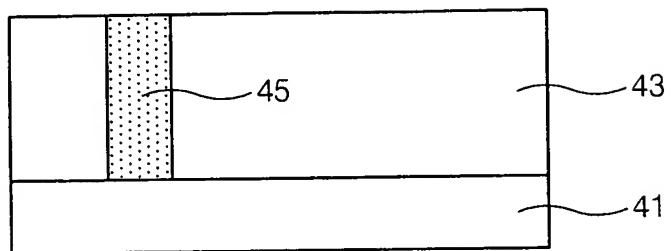


Fig.3a

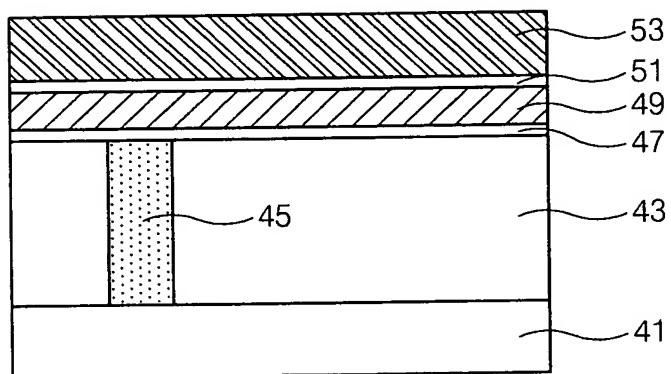


Fig.3b

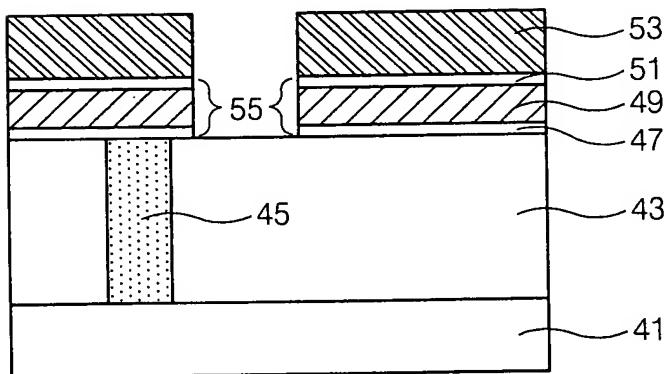


Fig.3c

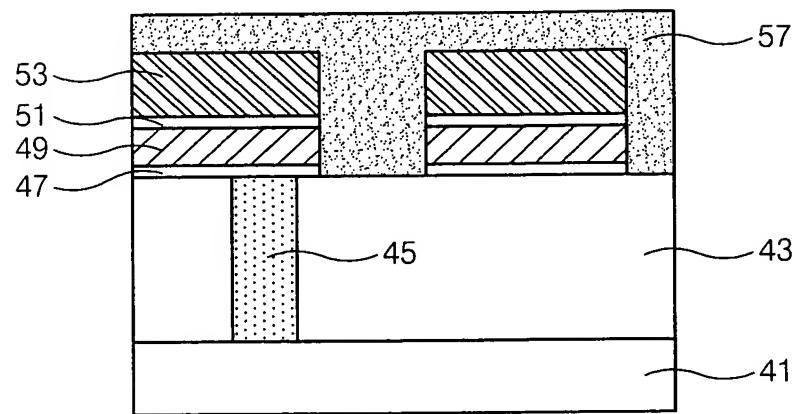


Fig. 3d

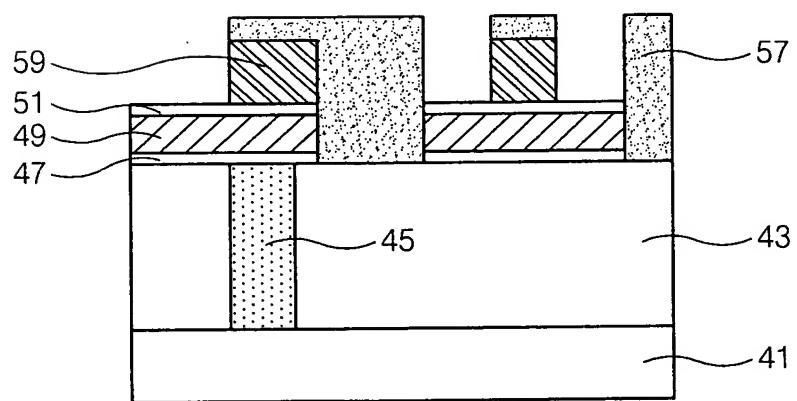


Fig. 3e

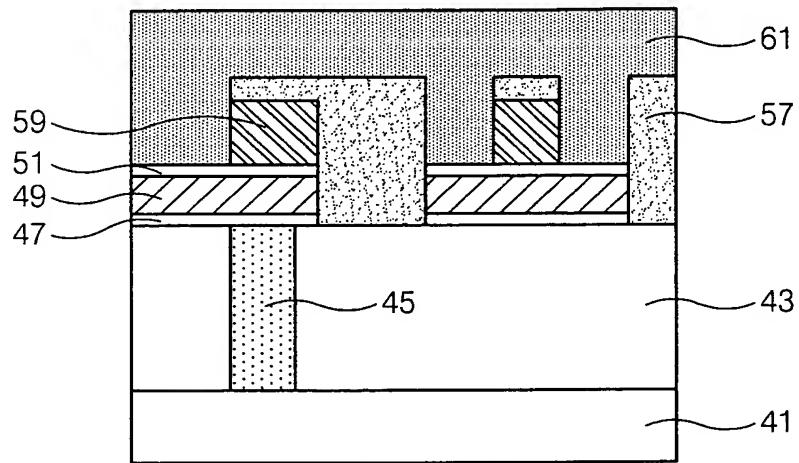


Fig.3f

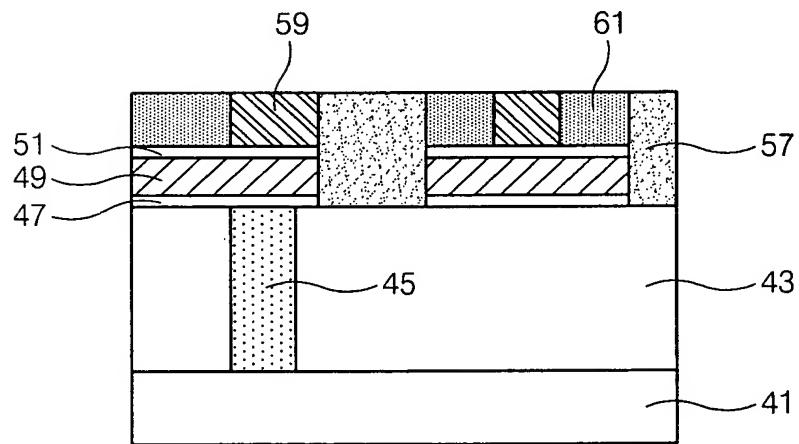


Fig.3g

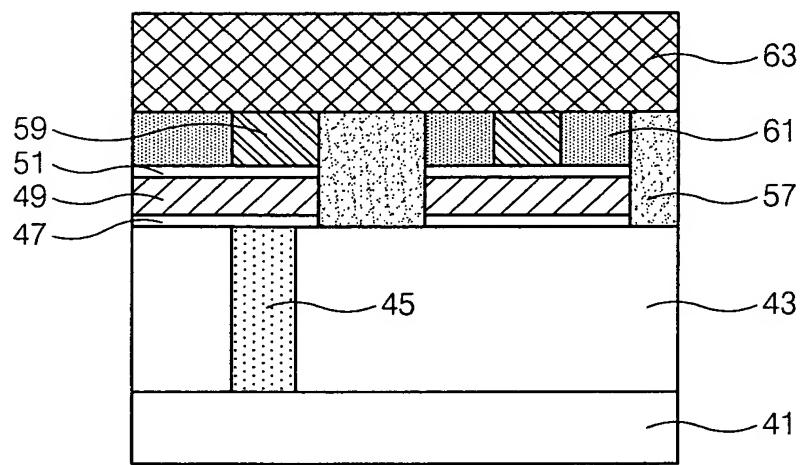


Fig.3h

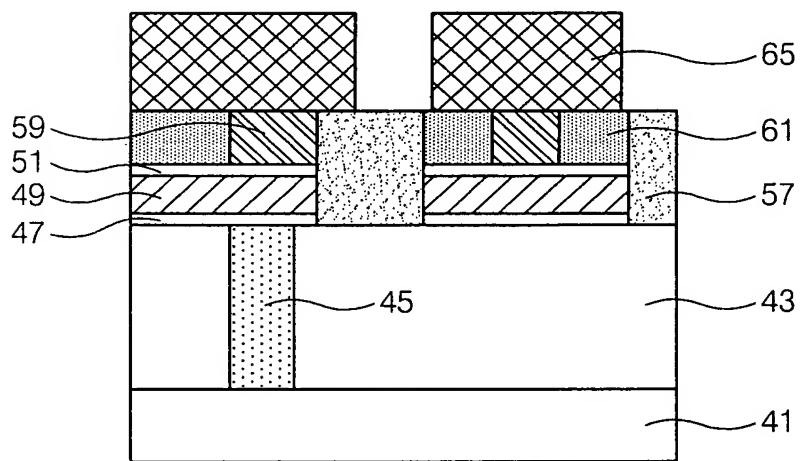


Fig.3i